



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant: SHINCHIRO YAGI Confirmation No.: 8468
Serial No.: 09/914,044 Atty Docket No.: 155/50324
Filed: December 11, 2001 Group Art Unit: 2851
Customer No.: 23911 Examiner: Fuller, Rodney Evan
Title: INSPECTION OBJECT SILICON WAFER FOR THE PURPOSE
OF DETECTING CRYSTAL DEFECTS AND THE METHOD OF
DETECTING THEREOF

LETTER TO THE OFFICIAL DRAFTSMAN SUBMITTING FORMAL
DRAWINGS

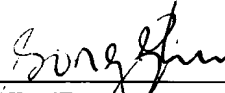
Mail Stop ISSUE FEE
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

2 sheets of Formal drawings (showing Figs. 3a, 3b, and 4) meeting the
requirements of 37 CFR § 1.84 are hereby submitted.

Respectfully submitted,

May 6, 2004

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